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APPLICATION NO.:

09/975,169

ATTY. DOCKET NO.: P0743/7001

FILING DATE:

October 11, 2001

APPLICANT:

Erik Deutsch et al.

GROUP ART UNIT:

2872

EXAMINER: Not Yet Assigned

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STATEMENT BY APPLICANT

APPLICATION NO.: 09/975,169 ATTY. DOCKET NO.: P0743/7001

FILING DATE: October 11, 2001

APPLICANT: Erik R. Deutsch et al.

GROUP ART UNIT: 2872 EXAMINER:

Sheet 1 of 6 GROUP ART UNIT:

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^{*}a copy of this reference is not provided as it was previously cited by or submitted to the office in a prior application, Serial No.________, filed________, and relied upon for an earlier filing date under 35 U.S.C. 120 (continuation, continuation-in-part, and divisional applications).

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ATTY. DOCKET NO.: P0743/7001 APPLICATION NO.: 09/975,169 FORM PTO-1449/A and B (Modified) INFORMATION DISCLOSURE October 11, 2001 FILING DATE: STATEMENT BY APPLICANT Erik R. Deutsch et al. APPLICANT: 2872 **EXAMINER: GROUP ART UNIT:** 2 6 Sheet of U.S. PATENT DOCUMENTS Date of Publication or of issue U.S. Patent Document Name of Patentee or Applicant of Cited Cite Examiner's of Cited Document Document Kind No. Initials # MM-DD-YY Number Code 01/14/98 Tayebati 5,739,945 05/18/99 5,905,571 Butler et al. 08/03/99 Troxell et al. 5,933,277 09/07/99 Koo et al. 5,949,568 10/12/99 Walker 5,966,235 10/19/99 Lee et al. 5,969,848 11/02/99 Berg 5,978,127 Jerman et al. 12/07/99 5,998,906 01/30/01 6,181,458 Brazas, Jr. et al. Hawkins et al. 06/26/01 6,252,697 FOREIGN PATENT DOCUMENTS Date of Foreign Patent Document Name of Patentee or Applicant of Cited Publication of Translation Cite Examiner's Cited Document (Y/N) No. Office/ Kind Initials # Document Number (not necessary) Code Country MM-DD-YY 06/14/01 ЖÓ 01/42825 A1 Gutin 02/15/01 01/11410 Thackara et al. WO A1 OTHER ART - NON PATENT LITERATURE DOCUMENTS Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the Translation Cite Examiner's item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue (Y/N) Initials # No number(s), publisher, city and/or country where published. POSITIONING, CONTROL, AND DYNAMICS OF ELECTROSTATIC ACTUATORS FOR USE IN OPTICAL AND RE SYSTEMS, E.S. HUNG, 08/21/98 thesis Massachusetts Institute of Technology, 107 pages MINIATURE FABRY-PEROT INTERFEROMETERS MICROMACHINED IN SILICON FOR USE IN OPTICAL FIBER WDM SYSTEMS, J.H. JERMAN et al., IEEE 1991 372, International Conf. On Solid-State Sensors and Actuators 1991, pp 372-375 MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON, K.E. PETERSEN, IBM Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523 LEVERAGED BENDING FOR FULL-GAP POSITIONING WITH ELECTROSTATIC ACTUATION, E.S. HUNG et al., MIT, Solid-State Sensor and Actuator Workshop Hilton Head Island, SC 06/08/98-06/11/98 pp 83-86 DATE CONSIDERED **EXAMINER** hem #EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through/citation if/not in conformance and not considered. Include copy of this form with next communication to applicant. *a copy of this reference is not provided as it was previously cited by or submitted to the office in a prior application, Serial No. , and relied upon for an earlier filing date under 35 U.S.C. 120 (continuation, continuation-in-part, and divisional applications).

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